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2877

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Bruce et al.	Examiner:	Turner, S.
Serial No.:	09/386,112	Group Art Unit:	2877
Filed:	August 30, 1999	Docket No.:	AMDA.261PA
Title:	DUAL-DIFFERENTIAL INTERFEROMETRY FOR SILICON DEVICE DAMAGE DETECTION		

17/B
G. Stanley
6-11-02

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence and the papers, as described hereinabove, are being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on March 5, 2002.

By: Erin M. Nichols
Erin M. Nichols

OFFICE ACTION RESPONSE AND AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

RECEIVED
MAR 27 2002
TECHNOLOGY CENTER 2800

Dear Sir:

In response to the Office Action dated December 5, 2001, please consider the following amendment and remarks.

In the claims

Please replace claim 11 as indicated below. The changes may be found on the attached sheet.

11. (Amended) A system for detecting a defect in a semiconductor device that includes a semiconductor die having a circuit side and bulk silicon in a back side opposite the circuit side, comprising:

a first beam splitter adapted for optical manipulation relative to the back side of the semiconductor die;

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